Description:

1. Electrical power: 400VAC, 3P+N, 32A, 50/60Hz, 63A
2. 300mm load port x2 (Asyst ISO port)
3. Brooks DBM 2406 dual arm robot
4. Wafer flip station x2 for wafer backside processing or front side processing
5. 300mm wafer process chamber x4
6. 300mm standard chuck x4 (to be confirmed)
7. FFU and Ion systems
8. CDS: integrated chemical cabinets x2
9. Med1
    - Dual inline heater
    - Equipped with Honda ultrasonic flow meters
    - Last ran production with HF-acetic acid, 60C
10. Med2
    - Buffer PZ10 spiking pump
    - Paddle wheel
    - Dual Inline heater
    - Cooling unit
    - Equipped with Honda ultrasonic flow meters
    - Last ran production with poly etch (HF:HNO3), 25C
11. Original manufacturer manual soft copy
12. Original hard disks with software at time of de-installation

Crate	L (cm)	W (cm)	H (cm)	W (kg)	Label
1	400	140	283	5255	Main Unit w/ FFU, CDS
2	102	75	173	440	EXT. RACK INCL PDB & TRAFO